

## PInano<sup>®</sup> Z Microscope Scanner System for Microtiter Plates

### Large Clear Aperture for Microtiter Plates, Low Profile, with Digital Controller



### **P-736**

- Fast step & settle
- Clear aperture for well plates and low profile for easy integration
- Travel range 220 µm
- Outstanding lifetime due to PICMA<sup>®</sup> piezo actuators
- Piezoresistive sensors for lower cost
- Capacitive sensors for higher stability

### **Fields of application**

Confocal microscopy 3D imaging Laser technology Interferometry Metrology / measuring technology Biotechnology Micromanipulation

### Precision-class nanopositioning system for high-resolution microscopy

Optimized for very fast step-and-settle. Exceptionally low profile of 18 mm for easy integration. Versions available for inverted microscopes from Nikon and Olympus.

### PICMA® piezo actuator drive

All-ceramic insulation for maximum operating time. Significantly higher humidity resistance. Excellent guiding accuracy due to FEA-modeled flexure joints.

### Choice of feedback sensors: piezoresistive or capacitive

- High-resolution piezoresistive sensors ensure stable position control

- Direct-measuring capacitive sensors for considerably improved stability and repeatability compared to piezoresistive sensors

### System with controller and software

The compact E-709 digital servo piezo controller is included in the delivery. Digital servos allow adaptation of all control parameters on the fly, by software. Control is possible via USB, RS-232 and a broadband analog interface. Supports PIMikroMove, NanoCapture. PI General Command Set (GCS). Drivers for LabVIEW, shared libraries for Windows and Linux. Compatible with µManager, MATLAB and Andor iQ.

| Motion            | Unit | P-736.ZRN2S | PD73Z2ROW | P-736.ZCN2S | PD73Z2COW |
|-------------------|------|-------------|-----------|-------------|-----------|
| Active axes       |      | Z           | Z         | Z           | Z         |
| Travel range in Z | μm   | 220         | 220       | 220         | 220       |

| Positioning            | Unit | P-736.ZRN2S                                      | PD73Z2ROW  | P-736.ZCN2S                           | PD73Z2COW                             |
|------------------------|------|--|--|---------------------------------------|---------------------------------------|
| Integrated sensor      |      | Piezoresistive, indirect posi-<br>tion measuring | Piezoresistive, indirect posi-<br>tion measuring | Capacitive, direct position measuring | Capacitive, direct position measuring |
| System resolution in Z | nm   | 1  | 1  | 1                                     | 1                                     |

| Drive Properties | P-736.ZRN2S | PD73Z2ROW | P-736.ZCN2S | PD73Z2COW |
|------------------|-------------|-----------|-------------|-----------|
| Drive type       | PICMA®      | PICMA®    | PICMA®      | PICMA®    |

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| Mechanical Properties                               | Unit | Tolerance | P-736.ZRN2S                                 | PD73Z2ROW                                   | P-736.ZCN2S                                 | PD73Z2COW                                   |
|---|------|-----------|---|---|---|---|
| Resonant frequency in Z, un-<br>der load with 100 g | Hz   | ±20%      | 250   | 250   | 250   | 250   |
| Permissible push force in Z                         | N    | Max.      | 5   | 5   | 5   | 5   |
| Guide   |      |           | Flexure guide with lever am-<br>plification |
| Overall mass  | g    | ±5%       | 850   | 850   | 850   | 850   |
| Material  |      |           | Aluminum                                    | Aluminum                                    | Aluminum                                    | Aluminum                                    |

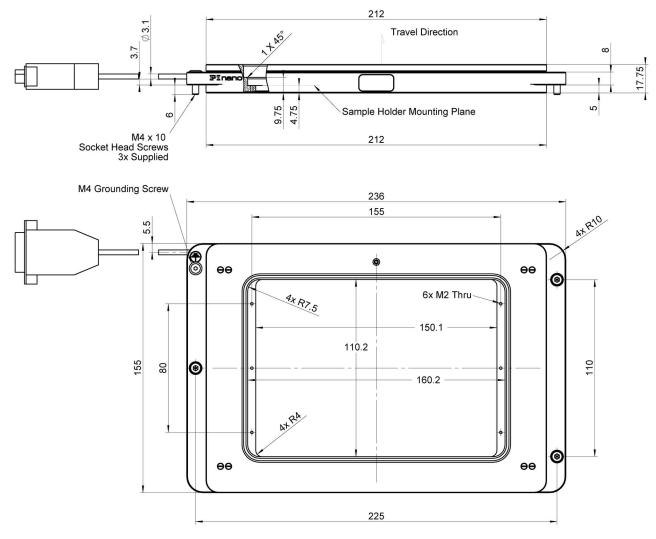
| Miscellaneous                        | Unit | Tolerance | P-736.ZRN2S                             | PD73Z2ROW                                 | P-736.ZCN2S                             | PD73Z2COW                                 |
|--------------------------------------|------|-----------|---|---|---|---|
| Operating temperature ran-<br>ge     | °C   |           | 15 to 40                                | 15 to 40                                  | 15 to 40                                | 15 to 40                                  |
| Connector                            |      |           | D-sub 9 (m)                             | D-sub 9 (m)                               | D-sub 7W2 (m)                           | D-sub 7W2 (m)                             |
| Cable length                         | m    | ±10 mm    | 1.7                                     | 1.7                                       | 1.7                                     | 1.7                                       |
| Compatible inverted micros-<br>copes |      |           | Nikon Eclipse Ti2   Nikon<br>Eclipse Ti | Olympus IX3   Olympus IX2<br>  Olympus IX | Nikon Eclipse Ti2   Nikon<br>Eclipse Ti | Olympus IX3   Olympus IX2<br>  Olympus IX |

| Controller                             | Unit | P-736.ZRN2S  | PD73Z2ROW  | P-736.ZCN2S  | PD73Z2COW  |
|--|------|--|--|--|--|
| Controller type                        |      | E-709 (included in the scope of delivery)  |
| Application-related functions          |      | Data recorder  | Data recorder  | Data recorder  | Data recorder  |
| Motion types                           |      | Wave generator   | Wave generator   | Wave generator   | Wave generator   |
| Communication interfaces               |      | RS-232   SPI   USB   | RS-232   SPI   USB   | RS-232   SPI   USB   | RS-232   SPI   USB   |
| Command set                            |      | GCS 2.0  | GCS 2.0  | GCS 2.0  | GCS 2.0  |
| User software                          |      | PIMikroMove  | PIMikroMove  | PIMikroMove  | PIMikroMove  |
| Software - APIs                        |      | Dynamic library for Pl Gene-<br>ral Command Set (GCS)   C,<br>C++, C#   MATLAB   NI Lab-<br>View   | Dynamic library for PI Gene-<br>ral Command Set (GCS)   C,<br>C++, C#   MATLAB   NI Lab-<br>View   | Dynamic library for Pl Gene-<br>ral Command Set (GCS)   C,<br>C++, C#   MATLAB   Nl Lab-<br>View   | Dynamic library for Pl Gene-<br>ral Command Set (GCS)   C,<br>C++, C#   MATLAB   Nl Lab-<br>View   |
| I/O lines                              |      | 1× analog input 0 to 10 V;<br>1× sensor monitor 0 to 10 V;<br>1× digital input (LVTTL, pro-<br>grammable); 1× analog out-<br>put; 5× digital outputs<br>(LVTTL, 3× predefined, 2×<br>programmable) | 1× analog input 0 to 10 V;<br>1× sensor monitor 0 to 10 V;<br>1× digital input (LVTTL, pro-<br>grammable); 1× analog out-<br>put; 5× digital outputs<br>(LVTTL, 3× predefined, 2×<br>programmable) | 1× analog input 0 to 10 V;<br>1× sensor monitor 0 to 10 V;<br>1× digital input (LVTTL, pro-<br>grammable); 1× analog out-<br>put; 5× digital outputs<br>(LVTTL, 3× predefined, 2×<br>programmable) | 1× analog input 0 to 10 V;<br>1× sensor monitor 0 to 10 V;<br>1× digital input (LVTTL, pro-<br>grammable); 1× analog out-<br>put; 5× digital outputs<br>(LVTTL, 3× predefined, 2×<br>programmable) |
| Controller's dimensions                |      | 160 mm × 96 mm × 33 mm   | 160 mm × 96 mm × 33 mm   | 160 mm × 96 mm × 33 mm   | 160 mm × 96 mm × 33 mm   |
| Drive functions                        |      | Autozero   | Autozero   | Autozero   | Autozero   |
| Motion-dependent inputs and outputs    |      | Digital trigger input   Digital<br>trigger output  |
| Integration with third-party solutions |      | MetaMorph   µManager  <br>Andor iQ   | MetaMorph   μManager  <br>Andor iQ   | MetaMorph   μManager  <br>Andor iQ   | MetaMorph   μManager  <br>Andor iQ   |

Permissible push force in Z: The recommended load for dynamic operation is 500 g (max.). Higher dynamics are possible with a reduced load.

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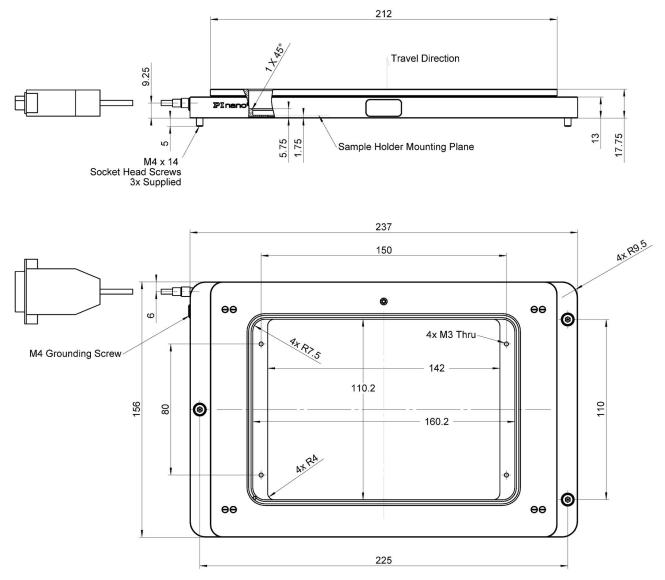
## Drawings / Images



P-736.ZCN2S / P-736.ZRN2S systems: Dimensions of the P-736.ZCN2 / P-736.ZRN2 mechanics in mm.



## Drawings / Images



PD73Z2COW / PD73Z2ROW systems: Dimensions of the P-736.ZCO / P-736.ZRO mechanics in mm.

## Drawings / Images



Customized designs are possible. The example above shows a P-736 version with particularly large aperture. The P-736 is mounted on an XY stage, which is driven by PILine<sup>®</sup> piezo motors.

## **Order Information**

### P-736.ZRN2S

PInano® Z piezo scanner system with clear aperture for microtiter plates; for inverted Nikon microscopes; 220 µm travel range; piezoresistive sensors; with USB digital controller

### PD73Z2ROW

Plnano<sup>®</sup> Z piezo scanner system with clear aperture for microtiter plates; for inverted Olympus microscopes; 220 µm travel range; piezoresistive sensors; with USB digital controller

### P-736.ZCN2S

PInano® Z piezo scanner system with clear aperture for microtiter plates; for inverted Nikon microscopes; 220 µm travel range; capacitive sensor; with USB digital controller

### PD73Z2COW

PInano® Z piezo scanner system with clear aperture for microtiter plates; for inverted Olympus microscopes; 220 µm travel range; capacitive sensor; with USB digital controller